

Center for Nanoscale Systems (CNS) – Harvard University  
Non-Academic Rates (effective 11/01/09, subject to change)

Imaging and Analysis Facilities

INSTRUMENT	Rate/ Unit	On-Site Staff Assistance	Remote Staff Assistance	Notes
TEM-6 Zeiss Libra200 a-corrected FEG STEM TEM-7 Zeiss Libra200 a-corrected FEG TEM	\$300/hour	\$150/hour	\$200/hour	
TEM-5 Technai Cryo-Bio FEG TEM	\$300/hour	\$150/hour	\$200/hour	
HAR-001 JEOL 2010 FEG TEM/STEM	\$300/hour	\$150/hour	\$200/hour	
HAR-027 JEOL 2100 TEM	\$300/hour	\$150/hour	\$200/hour	
SEMs (LEO SEM, Ultra55, Supra55, Zeiss EVO)	\$200/hour	\$150/hour	\$200/hour	5
SEM-7 Orion Helium Ion Microscope	\$200/hour	\$150/hour	\$200/hour	
HAR-34 Freeze Etching System	\$250/hour	\$150/hour	\$200/hour	
HAR-017 Ultramicrotome	\$100/hour	\$150/hour	\$200/hour	
B15A Sample prep tools: 1040 NanoMill	\$250/use	\$150/hour	\$200/hour	
HAR-037 1010 Dual beam Ion-mill	\$100/use	\$150/hour	\$200/hour	
HAR-024 Cressington Sputter Coater	\$120/use	\$150/hour	\$200/hour	
HAR-030 Baltec Sputter Coater	\$50/use	\$150/hour	\$200/hour	
CD-2 Critical Point Dryer	\$50/use	\$150/hour	\$200/hour	
HAR-019 Cryoplunge	\$50/use	\$150/hour	\$200/hour	
HAR-009 Gatan 691 Ion Mill	\$50/use	\$150/hour	\$200/hour	
HAR-008 Plasma Cleaner	\$50/use	\$150/hour	\$200/hour	
General Imaging Staff Assistance	N/A	\$150/hour	\$200/hour	4
Monthly Cap / user	\$7,500	none	none	

1. Self-use is charged at the base rate.
2. The on-site or remote staff assistance rates are in addition to any equipment rate.
3. In addition to actual time used in the logbook, users will be charged for all unused time reserved in the Scheduling Tool.
4. CNS staff assistance for all equipment training and certification, preparation of samples, or use of tools not listed above is charged at the General Staff Assistance rate. On-site and remote assistance are not included in cap.
5. The LEO A SEM is located in the LISE Cleanroom. The General LISE Cleanroom Access charge applies when using this tool (See Nanofabrication Facilities Rate Sheet).

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Materials Synthesis and Characterization Facilities

INSTRUMENT	Rate/ Unit	On-Site Staff Assistance	Remote Staff Assistance	Notes
FIB-2 Zeiss Nvision40 FIB	\$350/hour	\$150/hour	\$200/hour	
FIB-3 Zeiss Nvision40 FIB	\$350/hour	\$150/hour	\$200/hour	5
G05 Bio-Materials Facility	\$100/day	\$150/hour	\$200/hour	6
G06 Chemical Nanotechnology and SLF Facility	\$100/day	\$150/hour	\$200/hour	6
HAR-007 XPS ESCA SSX-100	\$200/hour	Included	\$200/hour	Assistance is required
HAR-018 Zeiss LSM510 Laser Scanning Confocal	\$200/hour	\$150/hour	\$200/hour	
HAR-028 Leica DM IRB Live Cell Microscope	\$200/hour	\$150/hour	\$200/hour	
MS-3 TIRF Laser Microscope	\$200/hour	\$150/hour	\$200/hour	
MS-4 Olympus FV300 Laser Scanning Confocal	\$200/hour	\$150/hour	\$200/hour	
LZR-2 Versalaser Cutting / Engraving System	\$100/hour	\$150/hour	\$200/hour	
SPM-1 Asylum AFM I	\$200/hour	\$150/hour	\$200/hour	
SPM-2 Asylum AFM II (Coax)	\$200/hour	\$150/hour	\$200/hour	
SPM-4 Witek NSOM	\$200/hour	\$150/hour	\$200/hour	
SW-1 DISCO Dicing Saw	\$100/hour	\$150/hour	\$200/hour	
XRA-2 X-Tek HMXST 225 MicroCT	\$200/hour	\$150/hour	\$200/hour	
General Materials Staff Assistance	N/A	\$150/hour	\$200/hour	
Monthly Cap / user	\$7,500	none	none	

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3. In addition to actual time used in the logbook, users will be charged for all unused time reserved in the Scheduling Tool.
4. CNS staff assistance for all equipment training and certification, preparation of samples, or use of tools not listed above is charged at the General Staff Assistance rate. On-site and remote assistance are not included in cap.
5. The FIB-3 is located in the LISE Cleanroom. The General LISE Cleanroom Access charge applies when using this tool (See Nanofabrication Facilities Rate Sheet).
6. Daily facility charges (G05 and G06) are charged for all tools within facility whether or not the tool has a separate hourly or per use charge.

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Nanofabrication Facilities

INSTRUMENT	Rate/ Unit	On-Site Staff Assistance	Remote Staff Assistance	Notes
General LISE Cleanroom Access	\$90/hr max \$270/day	\$150/hour	\$200/hour	5, 9
ALD-1 Savannah Atomic Layer Deposition	\$100/hour	\$150/hour	\$200/hour	
CVD-2 Nexx PECVD	\$250/hour	\$150/hour	\$200/hour	
CVD-3 STS PECVD	\$250/hour	\$150/hour	\$200/hour	
CVD-4,5,9,10 Atmospheric Furnace Tubes	\$200/hour	\$150/hour	\$200/hour	6
CVD-6,7,8,11 Low-Pressure Furnace Tubes	\$250/hour	\$150/hour	\$200/hour	6
RIE-6 Nexx RIE	\$250/hour	\$150/hour	\$200/hour	
RIE-7 Unaxis Shuttleline ICP RIE	\$250/hour	\$150/hour	\$200/hour	
RIE-8 STS ICP RIE	\$250/hour	\$150/hour	\$200/hour	
SPM-5 Veeco AFM	\$100/hour	\$150/hour	\$200/hour	
MET-1 Toho Stress Measurement System	\$100/hour	\$150/hour	\$200/hour	
EE-3 Sharon e-beam Evaporator	see note	\$150/hour	\$200/hour	7
EE-4 Denton e-beam Evaporator	\$250/hour	\$150/hour	\$200/hour	
SP-2 AJA Sputtering System	\$250/hour	\$150/hour	\$200/hour	
EL-1 Raith-150 e-Beam Lithography	\$280/hour	\$150/hour	\$200/hour	
EL-3 JEOL 7000F e-Beam Lithography	\$280/hour	\$150/hour	\$200/hour	
EL-4 Elionix STS7000 e-Beam Lithography	\$350/hour	\$150/hour	\$200/hour	
MW-1 Heidelberg Mask Writer	\$350/hour	Included	\$200/hour	6
PB-2 Lakeshore 1.5K Probe Station	\$150/hour	\$150/hour	\$200/hour	8
SW-2 Loomis Scriber	\$100/hour	\$150/hour	\$200/hour	
WB-1 Wire Bonder	\$100/hour	\$150/hour	\$200/hour	
FCB-1 Flip Chip Bonder	\$100/hour	\$150/hour	\$200/hour	
SW-3 Optical Fiber Fusion Splicer	\$250/hour	\$150/hour	\$200/hour	10
General Nanofab Staff Assistance	n/a	\$150/hour	\$200/hour	9
Monthly Cap / user	\$7,500	none	none	

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2. The on-site or remote staff assistance rates are in addition to any equipment rate.
3. In addition to actual time used in the logbook, users will be charged for all unused time reserved in the Scheduling Tool.
4. CNS staff assistance for all equipment training and certification, preparation of samples, or use of tools not listed above is charged at the General Staff Assistance rate. On-site and remote assistance are not included in cap.
5. General LISE Cleanroom Access fee is charged for all entries up to the daily maximum. The General Access fee also covers all cleanroom tools not otherwise listed on the rate sheet as having a separate charge.
6. Does not include masks or wafers. Available from staff for additional fee.
7. Market rates apply for use of crucible metal. Charges based on thickness used. Rates posted in cleanroom.
8. User must bring their own liquid helium (see tool web page for details).
9. General LISE Cleanroom Access Fee is not charged for Remote Staff Assistance usage.
10. Staff support is required, additional fee.